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PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10078720	FILING DATE 02/19/2002	CLASS 219	SUBCLASS 12122	GAU 1725	EXAMINER Elve
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**CONTINUING DATA VERIFIED:

** FOREIGN APPLICATIONS VERIFIED:

PG-PUB	DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>	ATTORNEY DOCKET NO 4795-004
Foreign priority claimed 35 USC 119 conditions met Verified and Acknowledged Examiner's initials		<input type="checkbox"/> yes <input type="checkbox"/> no <input type="checkbox"/> yes <input type="checkbox"/> no	U.S. DEPT. OF COMM. (PAT & TM)-PTC-438L (Rev. 12-94)
TITLE : Method and apparatus for cutting a substrate using laser irradiation			

NOTICE OF ALLOWANCE MAILED		CLAIMS ALLOWED		
		Assistant Examiner		
Amount Due	Date Paid	Total Claims	Print Claim for O.G.	
		DRAWING		
		Sheets Draw.	Fig. Draw.	Print Fig.
		Primary Examiner		
TERMINAL DISCLAIMER		Application Examiner		
PREPARED FOR ISSUE				
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